## Supporting Information

## Coupling piezoelectric and piezoresistive effects in flexible pressure sensors for human motion detection from zero to high frequency

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Fig. S1. Optical images of the flexible DMFS.



Fig. S2. The photo of DMFS array before and after leading wire.



**Fig. S3.** SEM image of GS/PVDF at lower magnification.



**Fig. S4.** The output peak voltage characteristics of DMFS at the applied frequency of 5, 10, and 20 Hz.

Mechanisms	Materials	Response	Recovery	Sensitivity	Ref.
		time (ms)	time (ms)		
Piezoelectric	ZnO	18.2	-	28.7 mV/N	[1]
Piezoelectric	PZT/PVDF	21	30	6.38 mV/N	[2]
Piezoelectric	PVDF/ZnO	16	16	0.33 V/kPa	[3]
Piezoelectric	PVDF	30	22	60.82 mV/N	[4]
Piezoelectric	PVDF	55	120	0.008 V/kPa	[5]
Piezoelectric	GaN/p-GaN	55	55	14.25 V/kPa	[6]
Piezoelectric	PZT/PDMS	-	-	8.59 mV/kPa	[7]
Piezoelectric	PZT	60	-	0.075 V/kPa	[8]
Piezoresistive	Au/PDMS	50	50	2.0 kPa <sup>-1</sup>	[9]
Piezoresistive	PDMS/CNT	48	-	0.34 kPa <sup>-1</sup>	[10]
Piezoresistive	MXene/Aramid	320	98	128 kPa <sup>-1</sup>	[11]
	nanofibers				
Piezoresistive	Graphene/paper	120	60	17.2 kPa <sup>-1</sup>	[12]
Piezoresistive	rGO/PDMS	120	80	25.1 kPa <sup>-1</sup>	[13]
Piezoresistive	MXene/PDMS	125	104	151.4 kPa <sup>-1</sup>	[14]
Piezoresistive	rGO/PANI	96	-	0.152 kPa <sup>-1</sup>	[15]
	sponge				
Piezoresistive	MXene-sponge	138	127	442 kPa <sup>-1</sup>	[16]
Piezoelectric	PVDF	25	25	830 mV/N	This
Piezoresistive	GS/PVDF	70	70	0.0005 kPa <sup>-1</sup>	work

Table S1. Comparison of performance with recent piezoelectric and piezoresistive pressure sensor.

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